

### ABSTRACT OF THE DISCLOSURE

A thermal physical vapor deposition source for depositing material onto a substrate includes an elongated container for receiving the material, the container having a conductance  $C_B$  in the elongated direction, and a heater for heating the material in the container to vaporize the material to a partial pressure  $P_m$ . The container has at least one member defining a plurality of apertures arranged along the length of the member, the apertures having a total conductance  $C_A$ , wherein  $\frac{C_A}{C_B} \leq 0.5$ , and end heaters for heating each side of the container to reduce condensation of material onto the container.